

Application/Control No.	Applicant(s)/Patent under Reexamination
10/646,152	3PARK ET AL.
Examiner	Art Unit
Shih-Chao Chen	2821

SEARCHED					
JEANOILE					
Subclass	Date	Examiner			
700MS, 702, 724, 725, 793, 853	3/5/2005	CHEN			
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	700MS, 702, 724, 725, 793,	700MS, 702, 724, 725, 793, 3/5/2005			

INTERFERENCE SEARCHED					
Class	Subclass	Date	Examiner		
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DATE 2/3/2005	CHEN
2/3/2005	CHEN